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PATENT
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventors: Tomohiro Makigaki, et al. Group Art Unit: 1746

Serial No.: 10/026,315 Examiner: S. Ahmed

Filed: December 20, 2001

Title: Ejection Device, Inkjet Head, Method Of Forming Nozzle For
Ejection Device And Method Of Manufacturing Inkjet Head

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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class mail in an envelope addressed to Assistant Commissioner for Patents, Washington, D.C. 20231 on this date.

Date: March 14, 2002

Ann F. George

03/28/2002 AD5MAN1 00000095 192746 10026315 PRELIMINARY AMENDMENT

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Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Preliminary to examination please amend the above identified application
as follows:

IN THE CLAIMS

Please add the following new Claims 2-21:

2. (New) A method of manufacturing an inkjet head according to claim 1, wherein the second groove is a ring groove defining the contour of the outer periphery of the through-hole.

3. (New) A method of manufacturing an inkjet head according to claim 1, wherein the upper substrate is a silicon substrate, and further comprising forming the first grooves and the second groove by dry-etching.

4. (New) A method of manufacturing an inkjet head according to claim 3, further comprising: using a resist film as a mask for the dry-etching, the resist film comprising a silicon-oxide-film; exposing the surface of the silicon substrate